

Form 1449 (Modified)	Atty Docket No. KLA1P015AD2/P611A2	Application No.: Unknown
Information Disclosure Statement By Applicant	Applicant: Lehman <i>et al.</i>	10/623953
(Use Several Sheets if Necessary)	Filing Date Herewith	Group 2862
		Not Assigned

U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class	Filing Date
RB	A1	5,552,704	9-3-96	Mallory, et al	—	—	
RB	A2	6,072,313	6-6-00	Li., et al	—	—	
RB	A3	5,559,428	9-24-96	Li, et al	—	—	
RB	A4	5,948,206	9-7-99	Inaba, et al	—	—	
RB	A5	4,849,694	7-18-89	Coates	—	—	
RB	A6	4,005,359	1-25-77	Smoot	—	—	
RB	A7	5,293,132	3-8-94	Koch	—	—	
RB	A8	35,703	12-30-97	Koch, et al	—	—	
RB	A9	5,930,744	7-27-99	Koch, et al	—	—	
RB	A10	5,001,356	3-19-91	Ichikawa	—	—	

Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Publication Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No
References not available at this time	B1	4132562 A1	9-30-91	Germany	—	—		X
	B2	0581703 A1	2-27-93	EPO	—	—		X
	B3	5-149927	6-15-93	Japan (abstract)	—	—	X	
	B4	64-12277	1-17-89	Japan (abstract)	—	—	X	
	B5	06311747 A1	12-28-94	EPO	—	—	X	

Other Documents

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
References not available at this time	C1	D.Shenton and Z. J. Cendes, "Eddy, Current Analysis Of Thin Film Recording Heads," March 15, 1984, American Institute of Physics
	C2	Steven A. Henck, "In Situ Real-time Ellipsometry For Film Thickness Measurement And Control," July/August 1992, American Vacuum Society.
Examiner	Date Considered	
Reena Sharma	7/26/09	

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.